



# Photo-amorphization and photo-oxidation of $\text{As}_{50}\text{Se}_{50}$ thin films deposited onto silicon substrates

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## Abstract

The photo-vitrification of  $\text{As}_{50}\text{Se}_{50}$  thin films deposited onto silicon wafer substrates is reported. This process, which was found to be athermal, has been studied using X-ray diffraction measurements, far infrared spectroscopy, EDAX-measurements, and scanning electron microscopy. When the crystallized films were illuminated in order to be amorphized, photo-oxidation of the thin-film samples was also detected. As a consequence, arsenic trioxide microcrystals were formed in the whole matrix of the films. Such behaviour has not been observed with  $\text{As}_{50}\text{Se}_{50}$  films deposited on glass substrates, which clearly demonstrates that the photo-vitrification phenomenon depends strongly on the type of substrate the  $\text{As}_{50}\text{Se}_{50}$  thin film is deposited on. The radiation source is another factor that clearly influences the light-amorphization of a previously crystallized  $\text{As}_{50}\text{Se}_{50}$  thin film. © 1998 Elsevier Science B.V. All rights reserved.

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## 1. Introduction

It has been observed that amorphous chalcogenides can suffer many light-induced structural changes [1]. These photo-structural changes when reversible, are only observed in well-annealed bulk glasses or amorphous thin films, where they can be removed by annealing near the glass transition temperature [2,3]. On the other hand, except for the metal photo-dissolution phenomenon, irreversible ef-

fects generally occur in metastable thin films. It has also been shown that illumination with high-intensity light can lead to photo-crystallization of amorphous  $\text{GeSe}_2$  [4]. In the present letter, we report on the athermal photo-induced vitrification of  $\text{As}_{50}\text{Se}_{50}$  thin films [5,6]. This process has only been observed when an  $\text{As}_{50}\text{Se}_{50}$  film is crystallized on a silica glass substrate. We present here, for the first time, the photo-vitrification process of  $\text{As}_{50}\text{Se}_{50}$  thin films deposited onto silicon wafer substrates. This photo-structural change will be discussed, not only in terms of far infrared spectroscopy, but also using X-ray diffraction (XRD) measurements.

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## 2. Materials and methods

Bulk samples were prepared by direct synthesis from high-purity elements (5N), heated together in an evacuated quartz ampoule, at a temperature of  $\approx 950^\circ\text{C}$ , for about 24 h. After the synthesis the melt was air-quenched, resulting in a bulk glass of the required chemical composition. The glassy nature of the ingot was checked using X-ray diffraction (Philips, model PW1710). Amorphous thin-film samples were prepared by vacuum evaporation of the  $\text{As}_{50}\text{Se}_{50}$  bulk glass onto silicon substrates. The thermal evaporation process was carried out in a coating system (Edwards, model E306A), at a pressure of  $\approx 10^{-6}$  Torr, from a suitable quartz crucible. Electron microprobe analysis of the as-deposited  $\text{As}_{50}\text{Se}_{50}$  thin films indicated that the film stoichiometry is correct within  $\pm 0.5$  at.%. The film thicknesses, in the range of approximately 700–1200 nm, were measured with a stylus-based surface profiler (Sloan, model Dektak 3030). The samples were annealed at  $\approx 150^\circ\text{C}$  for periods of time of, typically, 72 h in a  $\approx 10^{-3}$  Torr vacuum. The  $\text{As}_{50}\text{Se}_{50}$  films were illuminated by use of a 500 W Hg arc lamp (Oriel, model 66032), through an IR-cut filter, and using a light intensity of  $\approx 300$   $\text{mW cm}^{-2}$ . X-ray diffraction, using  $\text{Cu K}_\alpha$  radiation (1.54 Å), was used to examine the glassy or crystalline nature of the films. The IR transmission spectra were measured, at room temperature, by use of a computer-controlled FTIR spectrometer (Perkin-Elmer, model 2000), in the energy region 720–30  $\text{cm}^{-1}$ . The examination of the samples by scanning electron microscopy was carried out in a Jeol JSM-820 electron microscope.

## 3. Results and discussion

X-ray diffraction patterns of as-evaporated, annealed and illuminated  $\text{As}_{50}\text{Se}_{50}$  films, deposited onto silicon wafers are shown in Fig. 1. It should be noted the presence of the first sharp diffraction peak (FSDP) in the XRD-patterns of the as-evaporated and illuminated films [5]. However, that feature is not present in the XRD-pattern of the crystallized product. The peak intensities measured in our experiments are different from the reference powder-dif-

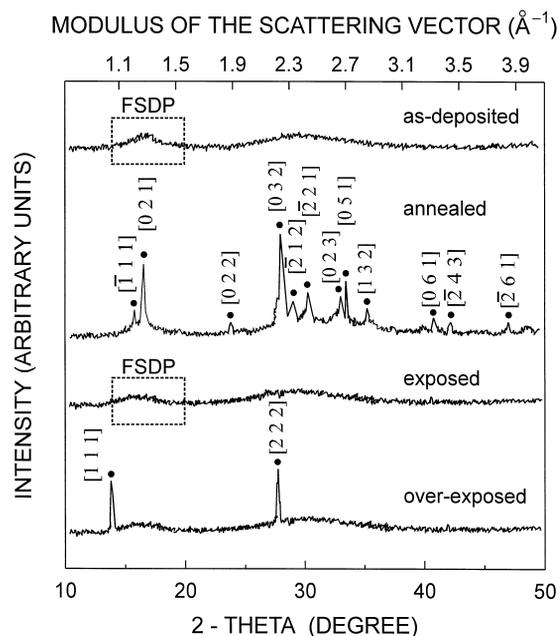


Fig. 1. XRD-patterns ( $\text{Cu K}_\alpha$  radiation) of the as-evaporated, crystallized, photo-verified and photo-oxidized  $\text{As}_{50}\text{Se}_{50}$  thin films, deposited onto silicon wafer substrates.

fraction data, due to the existence of preferred orientational effects in the crystallized films.

We found in a previous work [7], that the XRD-pattern of  $\text{As}_{50}\text{Se}_{50}$  crystallized films on glass substrates, present the most intense peaks at  $2\theta = 27.59^\circ$  and  $16.20^\circ$ . In addition, less intense peaks were observed at  $2\theta = 15.31^\circ$ ,  $28.58^\circ$ ,  $29.90^\circ$ ,  $32.64^\circ$  and  $48.05^\circ$ . If we compare these data with those obtained for  $\text{As}_{50}\text{Se}_{50}$  crystallized films on silicon substrates, more peaks are resolved in the latter case. Apart from the peaks already found in the former case (except the peak at  $2\theta = 48.05^\circ$ ), peaks at  $2\theta = 23.36^\circ$ ,  $33.06^\circ$ ,  $34.85^\circ$ ,  $40.45^\circ$ ,  $41.75^\circ$  and  $46.60^\circ$  are clearly present in the XRD-pattern of  $\text{As}_{50}\text{Se}_{50}$  films, deposited onto silicon substrates. Thus, we can certainly assume that the crystallization process, which takes place upon annealing of  $\text{As}_{50}\text{Se}_{50}$  glass films, is different, depending on the type of substrate involved. Furthermore, in both cases, the structure of  $\text{As}_{50}\text{Se}_{50}$  crystallized films is composed of  $\text{As}_4\text{Se}_4$  quasi-spherical molecules [7].

The crystallized  $\text{As}_{50}\text{Se}_{50}$  films were then exposed, in air, to white light from the mercury arc

lamp for a period of time of about 10 h, at room temperature, which caused the *complete* disappearance of the crystalline features in the XRD-pattern (see Fig. 1). This observation obviously implies the photo-amorphization of these  $\text{As}_{50}\text{Se}_{50}$  films. During the illumination process, the temperature increase of the films, as monitored by a thermocouple attached to the surface of the  $\text{As}_{50}\text{Se}_{50}$  films, was never more than  $\approx 25^\circ\text{C}$ . This observation gives unambiguous evidence of the athermal character of the photo-induced amorphous-state transformation.

However, one differentiating structural characteristic of the photo-vitrification process which takes place using a glass substrate [7], in relation to that which occurs when a silicon substrate is used, is the total disappearance of FSDP in the former. In the latter, the FSDP does *not* disappear, although it becomes somewhat broader in the light-amorphized state.

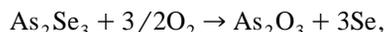
On the other hand, Elliott and Kolobov [5], used a quartz tungsten halogen lamp, and observed that both the XRD-patterns of as-evaporated and photo-vitrified  $\text{As}_{50}\text{Se}_{50}$  thin films, deposited onto glass substrates, show the same features, including the FSDP. This observation seems to suggest that the type of radiation source is another factor to be taken into account when an  $\text{As}_{50}\text{Se}_{50}$  crystallized film is to be light-amorphized.

Furthermore, the crystallization–vitrification process was found to be *reversible* with the present  $\text{As}_{50}\text{Se}_{50}$  films, deposited on silicon substrates. That means that the photo-vitrified film could again be crystallized by thermal annealing again at  $\approx 150^\circ\text{C}$ , and then, vitrified once more by the corresponding illumination. A similar behaviour was observed, when glass substrates were involved [6,7].

When the time of exposure of an  $\text{As}_{50}\text{Se}_{50}$  crystallized film, deposited onto a silicon substrate, was much longer than that mentioned earlier (in this particular case, we usually carried out the illumination for periods of time of  $\approx 20$  h), we found that *new* crystalline peaks arise upon irradiation of the film, as shown in Fig. 1. The XRD-pattern corresponding to the *over-exposed* sample could be explained in terms of a photo-oxidation of the film, and the consequent formation of arsenic trioxide crystals. This behaviour has certainly not been observed before during the photo-vitrification process, when glass

substrates were used and, apparently, is a characteristic of such photo-induced phenomenon when the thin-film sample is deposited onto silicon wafers.  $\text{As}_2\text{O}_3$  microcrystals were roughly identified compositionally by EDAX-measurements, and structurally by X-ray diffraction. Scanning electron microscope photomicrograph of the surface of the over-exposed  $\text{As}_{50}\text{Se}_{50}$  thin film, shows an arsenolite microcrystal (see Fig. 2).

On the other hand, the presence of chemical instability in amorphous  $\text{As}_2\text{Se}_3$  films has already been reported by Trubisky and Neyhart [8]. The decomposition of this glassy material was explained in terms of the following oxidation reaction:



taking place at the surface of the film. In fact, the oxidation process represented above is highly favourable, if we consider the calculated heat of that particular chemical reaction,  $\Delta H = -124$  kcal/mol.  $\text{As}_2\text{O}_3$  microcrystals were identified in this case and, consequently, that reaction seemed to describe the source of chemical instability in a- $\text{As}_2\text{Se}_3$  films. However, the possible effect of light was not studied in those experiments. The fact that  $\text{As}_2\text{O}_3$  microcrystals were much more numerous, when a- $\text{As}_2\text{Se}_3$  films had been stored under daylight conditions, compared to those that had been kept in complete darkness, clearly indicates that there is an important role played by the light in this oxidation process [1].

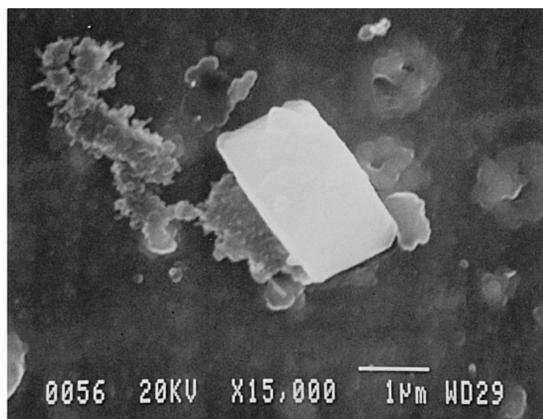


Fig. 2. Scanning electron microscope photograph of an  $\text{As}_{50}\text{Se}_{50}$  photo-oxidized film, where an arsenolite microcrystal can be seen.

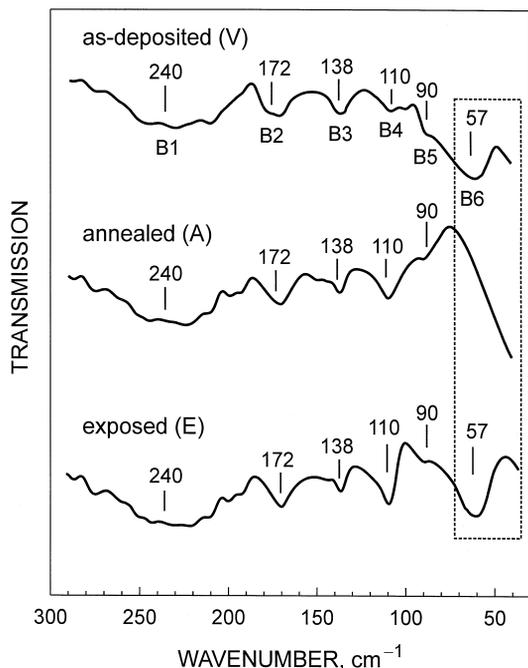


Fig. 3. Far infrared spectra of  $\text{As}_{50}\text{Se}_{50}$  thin films. V, virgin; A, after annealing; E, exposed.

Typical far infrared transmission spectra of as-deposited, annealed and exposed  $\text{As}_{50}\text{Se}_{50}$  films onto silicon substrates are presented in Fig. 3. The main infrared feature around  $240\text{ cm}^{-1}$ , in the spectrum of the as-deposited thin-film sample, corresponds to As–Se bond-stretching vibrations [9,10]. The pyramidal molecules  $\text{AsSe}_3$  and  $\text{As}_2\text{Se}_3$  are responsible for the absorption band at  $110\text{ cm}^{-1}$  [11,12], whereas the band at  $172\text{ cm}^{-1}$  is due to deformational vibrations of As–Se bonds [13]. Polymeric Se mode is observed at  $138\text{ cm}^{-1}$  (bond-bending mode of the Se chain) and  $\text{Se}_8$  rings at  $90\text{ cm}^{-1}$  [14,15]. Additionally, there is a strong absorption band at  $57\text{ cm}^{-1}$ .

On the other hand, the IR spectrum of the crystallized film shows the existence of absorption bands at wavenumbers very close indeed, to that already found in the IR spectrum of the as-deposited sample. Nevertheless, there is a very significant difference between those transmission spectra: the *complete* disappearance of the band at  $57\text{ cm}^{-1}$ , as a consequence of the thermal annealing process.

Finally, illumination with a Hg arc lamp of the annealed sample gives rise, again, to an absorption

band at  $57\text{ cm}^{-1}$ , in the IR spectrum of the corresponding photo-vitrified thin film. The other absorption bands observed in the IR spectra of the as-deposited and crystallized films are also present in the spectrum of the  $\text{As}_{50}\text{Se}_{50}$  photo-vitrified film.

#### 4. Conclusion

From the above results, we can certainly conclude, that there is a clear change in the absorption band at  $57\text{ cm}^{-1}$ , whereas the other IR bands remain practically unchanged. In addition, we have cycled annealing and illumination, and proved that the change observed in the IR absorption band at  $57\text{ cm}^{-1}$  is *reversible*. It should be pointed out that, in application of a molecular model to amorphous  $\text{As}_2\text{Se}_3$ , a calculated band at  $78\text{ cm}^{-1}$  has been ascribed to the antisymmetric bending vibration in  $\text{AsSe}_3$  pyramids [10]. A shift to the value of  $57\text{ cm}^{-1}$  could perhaps be explained assuming some changes in the angle and/or in the coordination of the As ‘central atom’. However, this is not clear since there could also exist some interlayer modes (i.e., van der Waals modes) (L. Tichý, private communication).

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